

Ion Beam Etch for Magnetic Sensors

- Select Veeco Applications:
 - AMR Wheatstone Bridge magnetic field sensor
 - GMR sensors for automotive
 - MRAM

Key IBE advantages:

- Etch rate control (angle)
- Process control and EPD
- Not sensitive to material type

Veeco advantages:

- Experience with magnetic material
- Custom application development
- High etch uniformity up to 200mm
- Production proven: automation and reliability

ETCH REQUIREMENTS EXAMPLE:

- Oxide over-etch < 50nm
- Clear metal between runners.
- Clear filaments from oxide sidewalls.

